

FORM PTO-1449

INFORMATION DISCLOSURE CITATION IN AN APPLICATION

(Use several sheets if necessary)

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Application Number
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Applicant
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Group Art Unit
Not Assigned

1011 U.S. PTO
10/016008

12/11/01

U.S. PATENT DOCUMENTS

EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
gd	5,447,890	09/1995	Kato et al.	437	249	

FOREIGN PATENT DOCUMENTS

	DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
						YES	NO
gd	EP 0782179	7/02/1997	EPO			X	
	EP 0337556	10/18/1989	EPO			X	
	WO 8912318	12/14/1989	PCT			x	
	EP 0764976	03/26/1997	EPO			x	
gd	JP06-114664	04/26/1994	JAPAN			Abstract	

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

gd	Current Status of 200 mm and 300 mm Silicon Wafers; Howard R. Huff et al.; 1998 Publication Board, Japanese Journal of Applied Physics; vol. 37, part 1, No. 3B March 1998; pp 1210-1216;
gd	Thickness Considerations in Direct Silicon Wafer Bonding; Q.Y. Tong et al., J. Electrochem. Soc., Vol. 142, No. 11; November 1995

EXAMINER

gd

DATE CONSIDERED

5/14/03

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to the applicant.